

aLIGO Waiver Log				waiver type					
Request DCC#	approved	rejected	Disposition DCC#	Subsystem	performance/ specification	process/procedure	vacuum/contamination	defect/ deviation	Description (title)
L080101		1	L080102	SYS		1	1		Request to relax the stipulation to use fully synthetic machining fluids when requesting parts with small surface area
L0900058		1	L100022	SUS			1		Request for waiver on glass shot blasted parts (BS/FM stay brackets)
L0900066	1		L1000178	SEI			1		Request for waiver on Viton material certification and restricted source for a small quantity of small o-rings
L1000343	1		L1000346	SYS			1		waiver request - vibratory tumbling for deburring (for mirror mounts)
L1000370		1	L1000375	SEI			1		waiver request for press-fit repairs to holes in machined aluminum parts of the HAM-ISI
L1100046	1		L1200067	SYS			1		waiver vacuum baking of optics
L1100162	1			SUS			1		VRB question: acceptable to not vacuum bake the CP and ERM to ESD flex connector bond?
C1102498	1		C1102498	VAC			1		Waiver to GNB re mid-station spool. FTIR baseline too high.
C1102502	1		C1102502	VAC				1	Waiver to GNB re MSS 1 Flange marks.
E1000610	1		E1000610	SEI			1		Waiver for the use of Ecocool AP-71 machining fluid for the sealing flange of the SEI storage containers
E1201079	1		E1201079	SEI			1		Machining Fluid Waiver Granted for SRI
E1400330	1		E1400330	ISC			1		Waiver for another RGA scan of the OMC Breadboard Assy, ASSY-D1201439
E1500061	1		E1500055	COC	1				BS01 AR absorption waiver
E1500062	1		E1500055	COC	1				BS02 AR absorption waiver
E1500063	1		E1500055	COC	1				BS03 AR absorption waiver
E1500064	1		E1500055	COC	1				BS04 AR absorption waiver
E1500065	1		C1101807	COC				1	BS03 polish waiver
E1500066	1		C1103274	COC				1	BS04 polish waiver
E1500067	1		C1101973	COC				1	BS05 polish waiver
E1500068	1		E1500055	COC	1				BS06 Absorption waiver
E1500069	1		E1500055	COC	1				CP09 absorption waiver
E1500070	1		C1002059	COC				1	ETM03 polish waiver
E1500071	1		bug 614 waiver	COC	1				ETM07 Coating, 532 nm reflection waiver
E1500072	1		G1100466	COC	1				ETM07 Coating, spherical aberration waiver
E1500073	1		T1300354	COC	1				ETM07 Coating, ripple waiver
E1500074	1		T1300354	COC	1				ETM08 Coating, ripple waiver
E1500075	1		T1300354	COC	1				ETM09 Coating, ripple waiver
E1500076	1		T1300354	COC	1				ETM10 Coating, ripple waiver
E1500077	1		T1400717	COC	1				ETM11 Coating, ripple waiver
E1500078	1		T1300354	COC	1				ETM12 Coating, ripple waiver
E1500079	1		T1300354	COC	1				ETM13 Coating, ripple waiver
E1500080	1		T1400717	COC	1				ETM14 Coating, ripple waiver
E1500081	1		T1300354	COC	1				ETM15 Coating, ripple waiver
E1500082	1		T1300354	COC	1				ETM16 Coating, ripple waiver
E1500083	1		T1300354	COC	1				ITM01 Coating, ripple waiver
E1500084	1		T1300354	COC	1				ITM03 Coating, ripple waiver
E1500085	1		T1300354	COC	1				ITM05 Coating, ripple waiver
E1500086	1		T1300354	COC	1				ITM06 Coating, ripple waiver
E1500087	1		T1300354	COC	1				ITM07 Coating, ripple waiver
E1500088	1		T1300354	COC	1				ITM09 Coating, ripple waiver
E1500089	1		T1300354	COC	1				ITM10 Coating, ripple waiver
E1500091	1		T1300354	COC	1				ITM11 Coating, ripple waiver
E1500092	1		T1400252	COC				1	ITM06 Coating, Haze on AR surface
E1500093	1		E1500093	COC				1	ITM09 Coating, Haze on AR surface, waiver
E1500094	1		E1500094	COC				1	ITM09, Mounting flat fracture, waiver
E1500095	1		G1100466	COC	1				ETM08 Coating, spherical aberration waiver
E1500096	1		G1100466	COC	1				ETM09 Coating, spherical aberration waiver
E1500097	1		G1100466	COC	1				ETM12 Coating, spherical aberration waiver

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E1500098	1		G1100466	COC	1				ETM11 Coating, spherical aberration waiver		
E1500099	1		G1100466	COC	1				ETM14 Coating, spherical aberration waiver		
E1500100	1		T1200295	COC	1				ITM04 Coating, spherical aberration waiver		
E1500101	1		T1200295	COC	1				ITM08 Coating, spherical aberration waiver		
E1500102	1		bug 614 waiver	COC	1				ETM08 Coating, 532 nm reflection waiver.		
E1500103	1		bug 614 waiver	COC	1				ETM09 Coating, 532 nm reflection waiver.		
E1500104	1		bug 614 waiver	COC	1				ETM12 Coating, 532 nm reflection waiver.		
E1500105	1		C1204263	COC				1	ETM12 Polish waiver		
E1500106	1		C1204263	COC				1	ETM13 Polish waiver		
E1500107	1		C1203264	COC				1	ETM11 Polish waiver, Barrel scuff		
E1500108	1		C1205170	COC				1	ETM14 Polish waiver, excess defects		
E1500109	1		C1103158	COC				1	ITM01 Polish waiver, excess defects		
E1500110	1		C1101807	COC				1	ITM03 Polish waiver, excess defects		
E1500111	1		C1002863	COC				1	ITM05 Polish waiver, excess defects		
E1500112	1		C1000386	COC				1	ITM06 Polish waiver, Bevel Defect		
E1500113	1		C1102248	COC				1	ITM11 Polish waiver, sleek		
E1500114	1		C1000357	COC				1	PR303 Polish Defect waiver		
E1500115	1		C1000619	COC				1	SR301 Polish Defect side and bevel fracture, waiver		
E1500116	1		C1000616	COC				1	SR301 Polish Defect Incorrect arrow and serial number placement, waiver		
E1500117	1		C1000616	COC				1	SR302 Polish Defect Incorrect arrow and serial number placement, waiver		
E1500118	1		C1000619	COC				1	SR302 Polish Defect side and bevel fracture, waiver		
E1500124	1		E1500122	COC	1				ETM08 ETM AR coating waiver		
E1500125	1		E1500122	COC	1				ETM12 ETM AR coating waiver		
E1500126	1		bug 4 waiver	COC	1				ITM09 AR coating waiver		
E1500127	1		bug 4 waiver	COC	1				ITM03 AR coating waiver		
E1500128	1		bug 4 waiver	COC	1				ITM11 AR coating waiver		
E1500129	1		bug 4 waiver	COC	1				ITM04 AR coating waiver		
E1500130	1		bug 4 waiver	COC	1				ITM08 AR coating waiver		
E1500131	1		E1500121	COC				1	ETM08 HR coating pinhole, waiver		
E1500132	1		E1500121	COC				1	ETM09 HR coating pinhole, waiver		
E1500149	1		T1000154	COC				1	ETM11 HR coating pinhole, waiver		
E1500123				IO		1			Fabrication Acceptance Review Status of Input Optics EOM Testing, Modeling and Discussion of need for Waivers from Systems		
L1300049	1		L1300049	SYS		1	1		Wiha (Hex) Allen Keys - waiver on bake		
L1100280	1		L1100280	TMS		1	1		Exceptions for NTE re: RFQ A0-301, quote response		
Q1100071	1		Q1100071	SUS				1	D020023 HSTS Structure Deviation Requests		
Q1500001	1		Q1500001	SLC		1	1		Waiver: Class B cleaning of 3 Alu parts for the SLC Elliptical Baffle		
Q1500002	1		Q1500002	SUS		1	1		Waiver: no bake for the H1 SR3 magnet repair		
Q1500003	1		Q1500003	SUS		1	1		Waiver: EP30 heat cure waiver for L1 SR3		
Q1500004	1		Q1500004	SUS		1	1		Waiver: to roughen surface of HLTS pen mass in situ		
Q1500005	1		Q1500005	SEI				1	Waiver: Arland Tool keensert repair proposal		
Q1500006	1		Q1500006	SUS		1	1		Waiver: no elevated temperature bake of adhesive for PR3 IM		
L070089	1		L070091	IO		1	1		Request for advice/waivers on some Input Optics elements		
Q1500007	1		Q1500007	VAC		1	1		Waiver: Class A Waiver Request for 6 blanks at LLO		
Q1500008	1		Q1500008	SUS		1	1		Waiver Request from Suspensions - room temp out-gassing cure of EP-30-2 on ITM-Y only		
Q1500009	1		Q1500009	SUS		1	1		Waiver: class B cleaning of AOSEM positioning brackets for the L1 PR3 SUS assembly		
Q1500010	1		Q1500010	SUS		1	1		Waiver: H1 PR2 AR magnet repair without elevated temperature cure		
Q1500011	1		Q1500011	SUS		1			Waiver: no impulse response, dynamic testing of the L1 BS with Elliptical Baffle		
Q1500012	1		Q1500012	ISC		1			Waiver: unapproved source and no material certs for some small Viton o-rings		
Q1500013	1		Q1500013	TMS		1	1		Waiver: dry machine, no clean and bake, 2 clamps for TMS		
Q1500014	1		Q1500014	SUS		1	1		Waiver for SmCo magnet/Al jacket assembly		

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E070288	1		L070097	IO		1	1	request for variance on vacuum procedure for IO supermirrors (request for vacuum waiver)	
M070383	1		M070383	ISC		1	1	cleaning waiver for ELI L1, 2" REO beamsplitter in HAM4	
Q1500015		1	Q1500015	VP		1	1	Cleaning Procedure Waiver Request for AR Coated and Uncoated Viewports	
Q1500016		1	Q1500016	VAC		1	1	Need waiver for Al in SS	
Q1500017		1	Q1500017	SEI		1	1	Need waiver for large parts	
Q1500018	1		Q1500018	SEI		1	1	Waiver: air bake 4 dowel pins for HAM-ISI actuator assy	
Q1500019	1		Q1500019	SEI		1	1	Waiver: air bake 50 barrel nuts	
Q1500020	1		Q1500020	ISC		1	1	Waiver: optics cleaning	
Q1500021	1		Q1500021	ISC		1	1	Waiver: DLC mount cleaning	
bug 20 waiver	1		L1200291	SYS	1			1 L1 Cpy ESD is inoperative	
bug 46 waiver	1		E1201105	IO				1 Reversal of wedge orientation for hanging PR3-01 in H1	
bug 195 waiver	1		T1300632	SYS				1 crack in PUM in ETMX suspension at LHO while welding	
bug 621 waiver	1		bug 621 waiver	SYS				1 LHO ITM03 crack	
bug 805 waiver	1		bug 805 waiver	SYS	1			IM3 (HAUX) first structural mode resonance non-compliance	